I claim:

- 1. A gripper device (4) for at least one of picking up, holding and conveying wafers (5), comprising
- a gripper element (13a-13c) which is arranged on a circuit board (10), the gripper element including at least one bipolar electrode pair (1) to which a voltage can be applied, and at least two gripper elements (1a-1c) being arranged on the circuit board, in which gripper elements the electrode pairs (1) are provided with an insulating layer (6) which predominantly comprises zirconium oxide.
- 2. The gripper device as claimed in claim 1, wherein the zirconium oxide is stabilized with yttrium oxide.
- 3. The gripper device as claimed in claim 1, wherein the gripper device comprises a flexible circuit board (10).
- 4. The gripper device as claimed in claim 1, wherein the gripper device comprises a flexible printed circuit board (10).
- 5. The gripper device as claimed in claim 1, wherein the electrode pairs (Figs. 1, 2) are at least one of round, and rectangular and finger-shaped.
- 6. The gripper device as claimed in claim 5, wherein in each case one pole (2) surrounds the other pole.
- 7. The gripper device as claimed in claim 1, wherein the gripper device can be operated with a DC voltage of at least one of less than 900 V and 600 V and 300 V.
- 8. The gripper device as claimed in claim 1, wherein when a component is being put down, an AC voltage can be applied shortly beforehand by grounding.

- 9. The gripper device as claimed in claim 1, wherein the electrode pairs (1a-1c) are arranged at a distance from each other, which is such that the wafer (5) can be lifted at its edges.
- 10. The gripper device as claimed in claim 1, wherein at least three electrode pairs (1a-1c) are arranged on a circular path.
- 11. The gripper device as claimed in claim 10, wherein three electrode pairs (1a-1c) are arranged at approximately 120° angles around the wafer.
- A process for producing an electrostatic gripper comprising one or more bipolar electrodes, comprising the steps of: applying the electrode pairs to a flexible circuit board (10); applying a mediation layer to the electrodes (1, 1a-1c); applying a zirconium oxide layer (6) to the mediation layer; applying an insulating layer (8) to the other side of the electrode; and pressing the layer assembly.
- The process as claimed in claim 12, wherein at least one of indium and nickel is applied 13. as mediation layer.
- 14. The process as claimed in claim 12, wherein the insulating layer is adhesively bonded before the pressing operation.
- The process as claimed in claim 12, wherein an insulating layer (8) that is coated with 15. adhesive is used.
- The process as claimed in claim 12, wherein aluminum (III) oxide is used as insulating 16. layer (8).
- 17. The process as claimed in claim 12, wherein first the electrodes are applied to a further flexible circuit board and are then applied to the flexible circuit board.

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